

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of :
 Fjelstad :
 : Group Art Unit: 2814
 CIP of Application No. :
 : Examiner: A. Chambliss
 Filed: Herewith :
 : Date: December 8, 2000
 For: METHODS FOR MANUFACTURING :
 RESISTORS USING A :
 SACRIFICIAL LAYER :
 X

Assistant Commissioner for Patents
 Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

PSir:

It is respectfully requested that the references listed on the enclosed Form PTO-1449 be made of record and considered with respect to the above-referenced U.S. patent application. A copy of each reference was of record in Application No. 09/409,205, the benefit of which is claimed under §120. Submission of the present Information Disclosure Statement should not be taken as an admission that the cited references are legally available prior art or that the same are pertinent or material.

In the event that any fee is due in connection with the present Information Disclosure Statement, the Commissioner is hereby authorized to charge the same to our Deposit Account No. 12-1095.

Respectfully submitted,

LERNER, DAVID, LITTENBERG,
 KRUMHOLZ & MENTLIK, LLP



MARCUS J. MILLET
 Reg. No. 28,241

600 South Avenue West
 Westfield, New Jersey 07090
 Telephone: (908) 654-5000
 Facsimile: (908) 654-7866
 IDS

EXPRESS MAIL LABEL NUMBER: EL458514861US

#6/IDS
 09/13/2001
 09/13/2001
 12/07/00